



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Akira HAMAMATSU et al.

Application No.:

10/050,776

Filed:

18 January 2002

For:

APPARATUS AND METHOD FOR INSPECTING DEFECTS

Art Unit:

2877

Examiner:

M.P. Stafira

Conf. No:

9567

## <u>PETITION FOR EXTENSION OF TIME</u>

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-14501

18 July 2005

Sir:

In the matter of the above-identified application, Applicant respectfully petitions the Commissioner for an extension of time set by the Notice of Appeal filed April 15, 2005. A Request for Continued Examination is submitted concurrently herewith. Please charge any fee deficiency to ATSK Deposit Account No. 01-2135.

Respectfully submitted,

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Concurrent Filings:

Request for Continued Examination Declaration Under 37 CFR 1.132